



Effects of Pd concentration on the interfacial reaction and mechanical reliability of the Sn–Pd/Ni system

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ABSTRACT

The liquid–solid reaction between Sn–Pd alloy and Ni ($x=0.05$ – 1 wt.%) and the resulting mechanical reliability of the system were examined in this study. The reactions strongly depended on the Pd concentration and the reaction time. When the Pd concentration was low (i.e., $x=0.05$ wt.%), the reaction product was only Ni₃Sn₄. In contrast, when the Pd concentration was high (i.e., $x \geq 0.2$ wt.%), the reaction product became a dual-layer structure of (Pd,Ni)Sn₄–Ni₃Sn₄. Between 0.05 wt.% and 0.2 wt.% (e.g., $x=0.1$ wt.%), discontinuous (Pd,Ni)Sn₄ grains scattered over the Ni₃Sn₄ layer developed. Interestingly, the (Pd,Ni)Sn₄ grains were gradually dispersed in the molten Sn–Pd alloy, leaving the Ni₃Sn₄ at the interface, as the reaction time increased. These Pd-dependent reactions were dictated by thermodynamics and can be rationalized using the Pd–Ni–Sn isotherm. Furthermore, the results of the high-speed-ball-shear (HSBS) test indicated that the mechanical strength of the Sn–Pd/Ni joints dramatically degraded by over one third due to the formation of (Pd,Ni)Sn₄ at the interface. The implication is that the Pd concentration in Sn–Pd solder joints should be reduced to a level below 0.2 wt.% to prevent the creation of an undesired microstructure.

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1. Introduction

Palladium-on-Ni(P) surface finishes, such as Pd/Ni(P) or Au/Pd/Ni(P), have recently received a great deal of attention in the microelectronics industry due to their low cost and high reliability in both wire-bonding and soldering applications [1,2]. In terms of soldering applications, the Ni(P) layer provides a good diffusion barrier between the solder and Cu trace, retarding pad consumption/intermetallic growth [3]. The surface Au serves as a protective layer against the oxidation of the Ni(P) finish. The insertion of a Pd (or Pd–P) film between Au and Ni(P) improves the wettability and acts as a diffusion barrier as well [4,5]. Additionally, the Pd film prevents the Ni(P) from the galvanic hyper-corrosion caused by the Au displacement reaction, thereby reducing the concern of “black pads” [1,6,7]. The thicknesses of the Au and Ni(P) deposited are customarily less than 0.1 μm and more than 5 μm, respectively, but that of the Pd layer has not yet been specified. The Pd film is preliminary deposited within the range of 0.05–0.3 μm (thickness) based on cost-effectiveness [1,8]. During soldering, the Pd layer quickly alloys with the molten solder at an early stage of soldering after the

surface Au is exhausted [9–11]. After the entire Pd layer is removed from the interface, the underlying Ni (or Ni–P) comes into contact with a solder containing various Pd concentrations, depending on the Pd thickness and joint dimensions.

The effect of the Pd concentration on the reaction between Ni and Sn–Pd alloys (Pd concentrations: 1, 3, and 5 at.%) at temperatures of 180 °C and 200 °C has been examined by Masui and Kajihara [12]. This reaction refers to a solid–solid reaction between Ni and Sn–Pd, which is a two-phase alloy consisting of β-Sn and PdSn₄ [13]. It was found that the PdSn₄ gradually migrates from the Sn matrix to the Sn–Pd/Ni interface during the solid-state reaction, enhancing the overall thickness (δ) of the reaction products. The δ follows a parabolic relationship with the reaction time, i.e., $\delta = kt^{0.5}$, where the growth coefficient k is one order of magnitude larger for 1–5% Pd than for 0% Pd. Thus, the Pd (or PdSn₄) has a significant influence on the reaction kinetics between the solid Ni and the solid Sn–Pd alloy [12].

The soldering reaction between Ni and Sn–Pd alloys at 250 °C was recently studied by Ho et al. [14]. The reaction refers to a solid–liquid reaction in which the Ni is a solid but the Sn–Pd alloy becomes a liquid (or paste), unlike that examined by Masui and Kajihara [12]. It was found that the solid–liquid reaction is much more sensitive to the Pd concentration, even with variations in concentration as low as 0.1 wt.%. At a low Pd concentration (e.g., 0.05 wt.%), only a layer of Ni₃Sn₄ grew at the interface. At a medium Pd concentration (e.g., 0.05–0.2 wt.%), a layer of Ni₃Sn₄ along with discontinuous (Pd,Ni)Sn₄ grains coexisted at the interface. At a high

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Pd concentration (e.g., 0.2–0.5 wt.%), the (Pd,Ni)Sn₄ grew as a layer over the Ni₃Sn₄. The Pd-dependent reaction is dictated by thermodynamics, and the details have been reported elsewhere in the literature [14].

In the aforementioned study [14], however, only one reaction time (120 s) within a narrow Pd concentration range (0.05–0.5 wt.%) was investigated. Results of the reaction at various times and high Pd concentrations are still quite lacking. The purpose of this study was to establish a more complete database, in which more reaction times (30–1200 s) and Pd concentrations (0.05–1 wt.%) are included, to provide a better understanding of the effect of the Pd concentration on the reaction between solid Ni and liquid Sn–Pd. Additionally, mechanical response of the Sn–Pd/Ni system was also investigated through a high-speed-ball-shear (HSBS) test.

2. Experimental details

The soldering reaction between Sn–xPd alloy and Ni, and the mechanical properties of the resulting Sn–xPd/Ni joints were examined in this study. The Ni was deposited over a 375- μm (d_{pad}) Cu pad by electroplating (Fig. 1), thereby making it free of P or V. The thickness of the Ni layer was about 7 μm and was not depleted during the soldering reaction. The Sn–xPd alloy was prepared from 99.99% pure Sn and 99.95% pure Pd, where x is 0.05, 0.1, 0.2, 0.3, 0.5, 0.7, and 1 wt.%, respectively. Each alloy was sealed in an evacuated quartz tube (5×10^{-3} Torr), mixed in a furnace setup at 900 °C for 3 days, and then quenched in water. The alloys were cross-sectioned before use, metallographically polished to ensure homogeneity, and subsequently shaped into solder balls with a diameter of 1200 μm (d_{joint}). These sol-

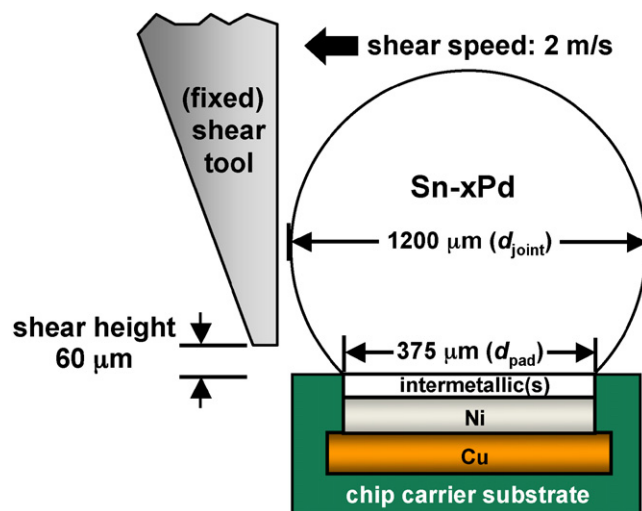


Fig. 1. Schematic diagram of a Sn–xPd solder joint under the high-speed-ball-shear (HSBS) test. A shear speed of 2 m/s was applied in shearing.

der balls were then planted onto individual pads, and at least fifteen solder joints were made for each solder composition and reaction time. Before the reaction, each pad was etched by a 30% HNO₃ aqueous solution and then smeared with a RMA (rosin mildly activated) flux to remove oxidized contaminations.

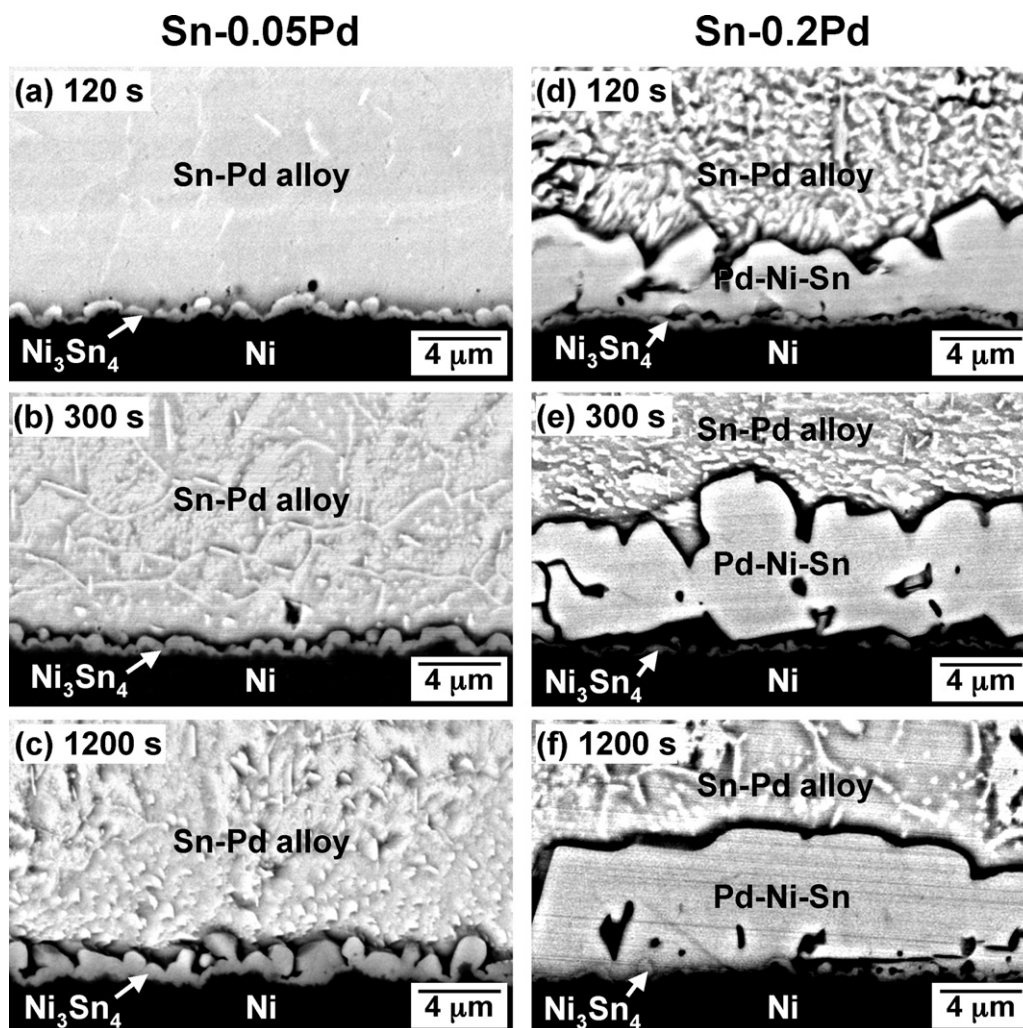


Fig. 2. Backscattered electron images (BEI) showing the Sn–xPd/Ni interfaces after reacting at 250 °C for 120 s (a and d), 300 s (b and e), and 1200 s (c and f). The x values were 0.05 (a–c) and 0.2 (d–f), respectively.

The soldering reaction was carried out at 250 °C for 30–1200 s. After the reaction, the solder joints were immediately quenched in water. A batch of solder joints was then cross-sectioned by a metallographical grinding–polishing process to reveal the detailed microstructures of the joints. The composition of each reaction product was determined by a field-emission electron probe micro-analyzer (FE-EPMA) operated at 12 keV. Such a low accelerated voltage produced a much smaller interaction volume between the incident electron beam and the measured specimen than that created by the traditional mode; thus, compositional measurements of some minute phases were possible. Additionally, a field-emission transmission electron microscopy (FE-TEM) (type: JEM-2100F) operated at 200 keV was employed to identify the crystal structures of the reaction products. The specimens for TEM examination were prepared using a focused ion beam (FIB) apparatus.

To evaluate the effect of the Pd concentration on the mechanical properties, another batch of solder joints was examined via the HSBS test. The shear test was carried out using a bond tester (type: DAGE 4000HS) according to the JESD22-B117 specification [15]. The shear speed and shear height were set to 2 m/s and 60 μm (Fig. 1), respectively. For each data point, at least ten measurements were made, and the average value was reported. The fracture surfaces of the solder joints after the HSBS test were examined using scanning electron microscopy–energy dispersive X-ray spectroscopy (SEM-EDX). Additionally, a micro X-ray photoelectron spectroscopy ($\mu\text{-XPS}$) with a spot size of about 9 μm was employed to pinpoint the exact position of the fracture.

3. Results

3.1. Low Pd-concentration case ($x = 0.05, 0.1, 0.2$, and 0.3)

Fig. 2 shows the cross-section of the Sn– x Pd/Ni interfaces ($x = 0.05$ and 0.2) that were reacted at 250 °C for 120 s (a and d), 300 s (b and e), and 1200 s (c and f). A clear trend in these reactions is that the amount of the reaction product(s) at the interface increased with the reaction time as well as the Pd concentration. Moreover, the type of reaction product produced is strongly dependent on x , even with a concentration differences as small as 0.15 wt.%.

The Sn–0.05Pd/Ni reaction produced a scallop-like compound layer at the interface for all of the times examined, as shown in Fig. 2a–c. With the aid of FE-EPMA, the compound was identified as Ni_3Sn_4 , with a very limited amount of Pd (~ 0.2 at.%) dissolved in it. The formation of intermetallic Ni_3Sn_4 at the interface is consistent with the soldering systems of Ni and most Sn-based alloys [16,17], excluding reactions alloying with additional active elements such as Cu [16,18] or Zn [19,20]. The type of reaction product (Ni_3Sn_4) observed did not change over time, but the thickness ($\delta_{\text{Ni}_3\text{Sn}_4}$) var-

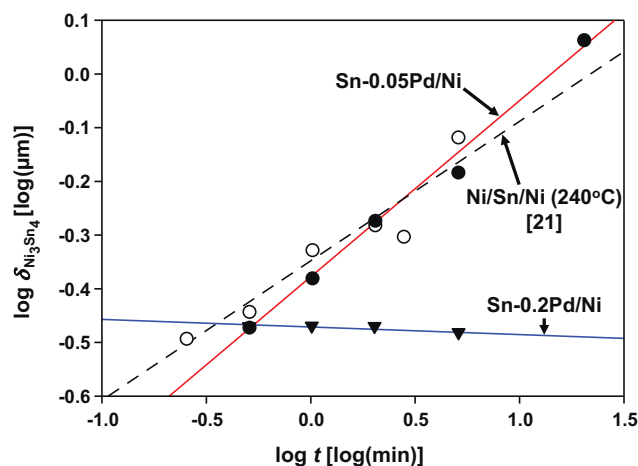


Fig. 3. Growth of the Ni_3Sn_4 phase in the Sn–0.05Pd/Ni, Sn–0.2Pd/Ni, and Ni/Sn/Ni reactions. The data of the Ni/Sn/Ni system (broken line) is adapted from the work of Bader et al. [21] and re-plotted in this study.

ied (Fig. 2a–c). Fig. 3 is a plot of $\log \delta_{\text{Ni}_3\text{Sn}_4} - \log t$, which provides a further illustration of the Pd effect on the Ni_3Sn_4 growth behavior. The $\delta_{\text{Ni}_3\text{Sn}_4}$ was measured using electron micrographs and a calibrated image analysis software. The thickness is defined as the phase area divided by a linear length of the interface. In the case of the Sn–0.05Pd/Ni reaction (red line), the r-square value is approximately 0.99, indicating that the measured data are closely fitted by linear regression. The slope and intercept values computed from the red line were 0.33 and -0.38 , respectively. Accordingly, the growth thickness of Ni_3Sn_4 in this case (i.e., Sn–0.05Pd/Ni) increased linearly as a function of $0.42t^{0.33}$. This observation suggests that the growth kinetics of Ni_3Sn_4 for the Sn–0.05Pd/Ni reaction is dominated by neither the diffusion-controlled mechanism nor the reaction-controlled mechanism. This growth behavior is very similar to that of $\delta_{\text{Ni}_3\text{Sn}_4} = 0.45t^{0.28}$ (as the broken line in Fig. 3) reported in the literature [21], where a thin Ni/Sn/Ni diffusion couple was utilized and a short-circuit diffusion mechanism was proposed to be the root cause of the unique growth [17]. The results above indicate

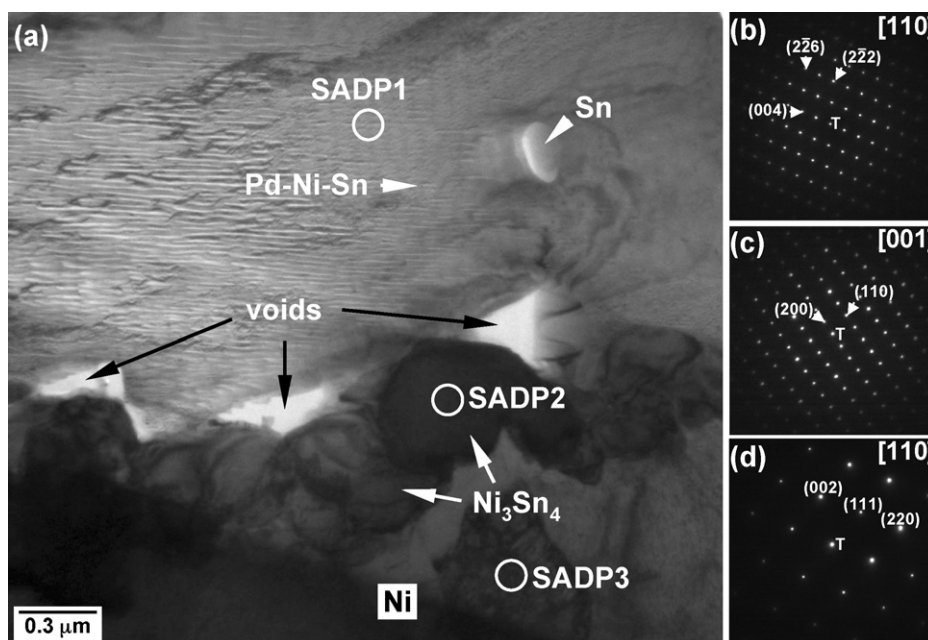


Fig. 4. (a) TEM bright field image of the Sn–0.2Pd/Ni interface after reacting at 250 °C for 120 s. (b–d) Selected-area diffraction patterns (SADPs) from (Pd,Ni) Sn_4 (SADP1), Ni_3Sn_4 (SADP2), and Ni (SADP3), respectively.

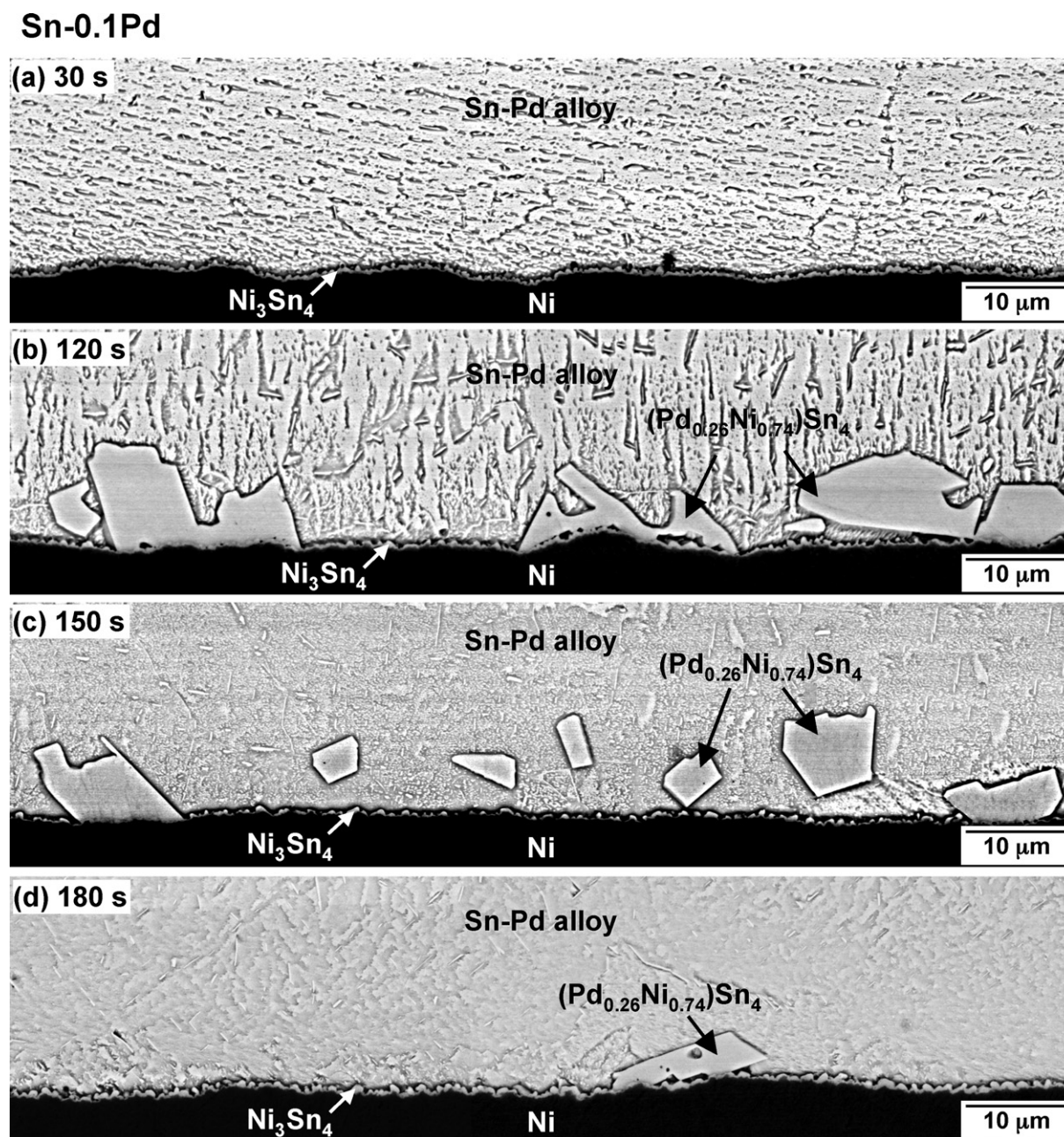


Fig. 5. Backscattered electron images showing the Sn-0.1Pd/Ni interfaces after reacting at 250 °C for 30 s (a), 120 s (b), 150 s (c), and 180 s (d).

that the addition of 0.05 wt.% Pd has a minor effect on the soldering reaction between Ni and Sn.

In contrast, there were two adjacent compound layers that nucleated at the interface when x increased to 0.2 (Fig. 2d–f). The layer neighboring the Ni was extremely thin and was identified using FE-EPMA as Ni₃Sn₄, as was obtained in the Sn-0.05Pd/Ni case. Interestingly, the thickness of the Ni₃Sn₄ layer did not increase with the reaction time but remained approximately the same at all times examined (Fig. 2d–f and Fig. 3). A further discussion of this unique growth mechanism is given in the subsequent section (Section 4.2).

The second layer, which grew between Ni₃Sn₄ and the Sn-Pd alloy, was much thicker than Ni₃Sn₄, as shown in Fig. 2d–f. The composition was determined using EPMA to be 7.7–8.9 at.% Pd, 10.9–14.3 at.% Ni, and 78.4–80.2 at.% Sn, which deviates from all of the possible intermetallics existed in the Ni–Sn binary system, e.g., Ni₃Sn, Ni₃Sn₂, and Ni₃Sn₄. The formation of this Pd–Ni–Sn

compound is not a transient phenomenon and can persist for at least 1200 s (Fig. 2f). The progressive growth of the Pd–Ni–Sn layer, as shown in Fig. 2d–f, indicates that the phase was produced when the Ni contacted the molten Sn-0.2Pd alloy, rather than at the stage of solidification. In other words, the Pd–Ni–Sn compound layer was not a product derived from precipitation due to the solubility limit.

Fig. 4 shows a TEM micrograph of the Sn-0.2Pd/Ni interface, together with selected-area diffraction patterns (SADPs). From top to bottom, the layers are Pd–Ni–Sn, Ni₃Sn₄, and Ni phases. The Sn–Pd alloy is above the Pd–Ni–Sn layer and is not shown in Fig. 4. The Pd–Ni–Sn phase has the PdSn₄-based crystal structure, as evidenced by the SADP shown in Fig. 4b, which agrees well with the EBSD results obtained in the literature [14]. Further examination using TEM-EDX shows that the Pd–Ni–Sn has a composition of 7.3 at.% Pd–13.1 at.% Ni–79.6 at.% Sn (average), which approximates the measurements made via EPMA. This composition was

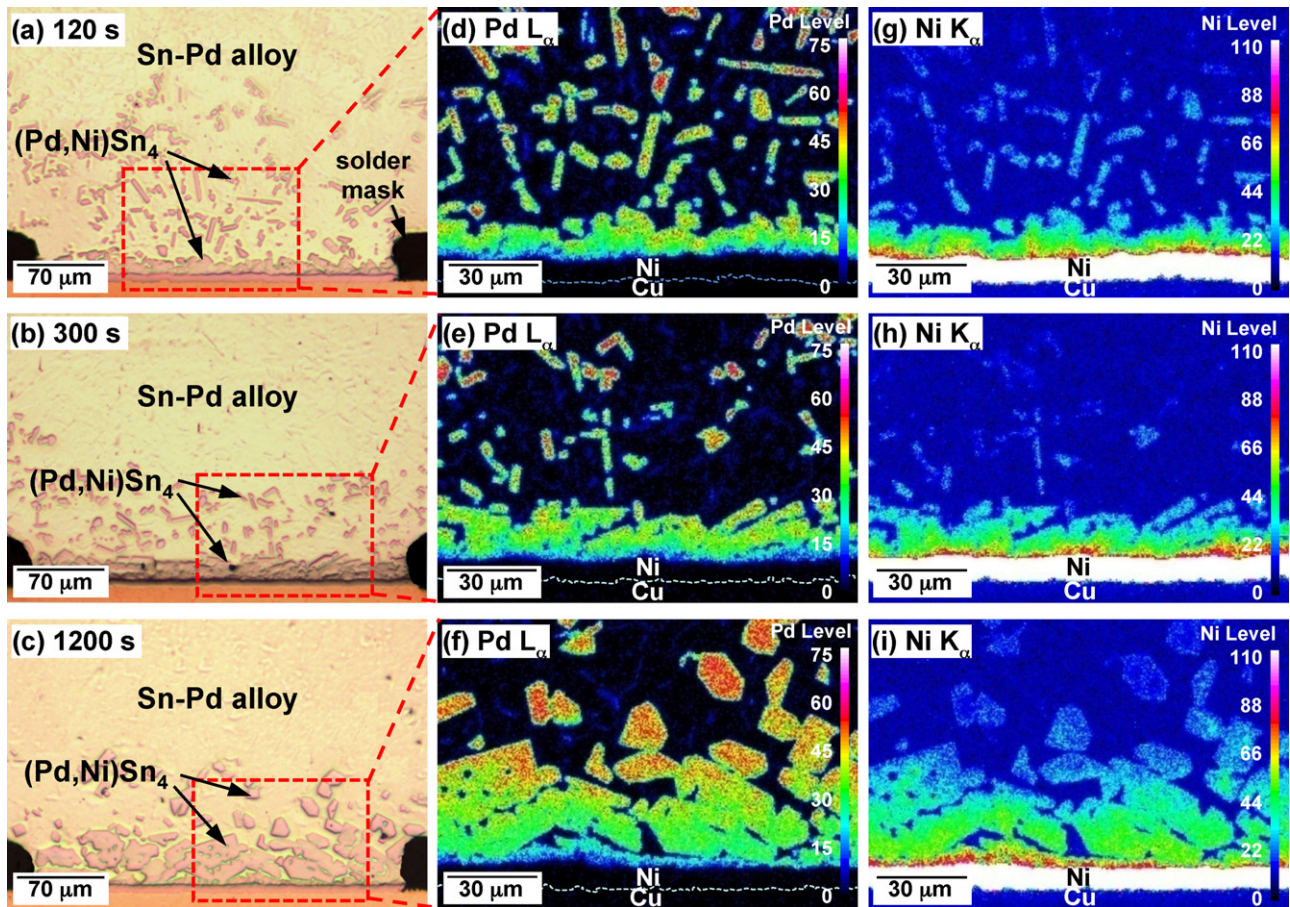


Fig. 6. (a–c) Optical micrographs showing the reaction zones between Sn–0.5Pd and Ni after reacting at 250 °C for 120 s, 300 s, and 1200 s, respectively. EPMA elemental mappings of Pd (d–f) and Ni (g–i) corresponding to the regions labeled by the squares in (a–c).

also very similar with the phase (i.e., $(\text{Pd}_{0.35}\text{Ni}_{0.65})\text{Sn}_4$) neighboring the Sn–Ni alloy of the Sn–Ni/Pd system [22]. These results show that a significant amount of Ni replaced the Pd sublattice sites of the PdSn_4 crystal. Accordingly, the Pd–Ni–Sn compound should more accurately be referred to as the $(\text{Pd,Ni})\text{Sn}_4$ stoichiometry. Immediately adjacent to the $(\text{Pd,Ni})\text{Sn}_4$ phase was a Ni_3Sn_4 layer with grain sizes of $\sim 0.4 \mu\text{m}$ (Fig. 4a and c). Additionally, there was a chain of voids that appeared between Ni_3Sn_4 and $(\text{Pd,Ni})\text{Sn}_4$, which has not been observed at the Sn–0.05Pd/Ni interface. Beneath Ni_3Sn_4 was a crystalline Ni metallization pad (Fig. 4a and d). This crystalline rather than amorphous structure reflects the fact that the Ni pads of this study were deposited by electroplating instead of electroless-plating.

When the Pd concentration was between 0.05 wt.% and 0.2 wt.%, e.g., 0.1 wt.%, the type of reaction product produced became time-dependent, as shown in Fig. 5a–d. At 30 s, there was only one compound layer Ni_3Sn_4 nucleated at the Sn–0.1Pd/Ni interface (Fig. 5a). At 60 s or 120 s, one additional $(\text{Pd,Ni})\text{Sn}_4$ compound with an average composition of $(\text{Pd}_{0.26}\text{Ni}_{0.74})\text{Sn}_4$ appeared at the Sn–0.1Pd/ Ni_3Sn_4 interface (Fig. 5b). The $(\text{Pd}_{0.26}\text{Ni}_{0.74})\text{Sn}_4$ exhibits a discontinuous, facet-type morphology unlike the layered-type structure produced at the Sn–0.2Pd/Ni interface (Fig. 2d–f). By prolonging the reaction time to 150 s, the amount of $(\text{Pd}_{0.26}\text{Ni}_{0.74})\text{Sn}_4$ present was reduced due to the fact that part of the $(\text{Pd,Ni})\text{Sn}_4$ grains spalled into the solder (Fig. 5c). At 180 s, most of the $(\text{Pd}_{0.26}\text{Ni}_{0.74})\text{Sn}_4$ grains disappeared, but the Ni_3Sn_4 layer survived (Fig. 5d). Consequently, the overall thickness of the reaction product(s), i.e. $(\text{Pd,Ni})\text{Sn}_4$ and Ni_3Sn_4 , did not always increase over time

in the case of Sn–0.1Pd; instead, it increased first (Fig. 5a and b) and then decreased gradually (Fig. 5c and d).

3.2. High Pd-concentration case ($x \geq 0.5$)

Fig. 6 shows optical micrographs together with EPMA elemental mappings of the Sn–0.5Pd/Ni interface after reacting for 120 s (a, d and g), 300 s (b, e and h), and 1200 s (c, f and i). These micrographs are representative of the high Pd-concentration case subsequently. The most remarkable difference from the Sn–0.2Pd case (Fig. 2d–f) is that two distinct $(\text{Pd,Ni})\text{Sn}_4$ layers existed as x increased to 0.5. At the interface, the $(\text{Pd,Ni})\text{Sn}_4$ layer was irregular and much thicker than that obtained in the low Pd-concentration case. Beneath the $(\text{Pd,Ni})\text{Sn}_4$ layer, there was a very thin Ni_3Sn_4 layer such as that grew in the Sn–0.2Pd/Ni case (Fig. 2d–f). However, the space between $(\text{Pd,Ni})\text{Sn}_4$ and Ni_3Sn_4 was occupied by the solder, unlike the voiding mentioned above (Fig. 2d–f and Fig. 4). The region in the solder matrix neighboring the interface was a two-phase mixture layer composed of solder and an aggregate of isolated $(\text{Pd,Ni})\text{Sn}_4$ domains. The thickness of the $(\text{Pd,Ni})\text{Sn}_4$ at the interface increased, but the extent of the two-phase layer of $(\text{Pd,Ni})\text{Sn}_4$ + solder reduced as a function of the reaction time.

Another interesting finding is that the composition of the $(\text{Pd,Ni})\text{Sn}_4$ varied with location. The EPMA elemental mappings presented in Fig. 6d–i clearly show that the Pd content of the $(\text{Pd,Ni})\text{Sn}_4$ increases progressively from the interface towards the solder region (d–f), whereas the Ni concentration shows the opposite trend (g–i). The Ni concentration of the $(\text{Pd,Ni})\text{Sn}_4$ reached

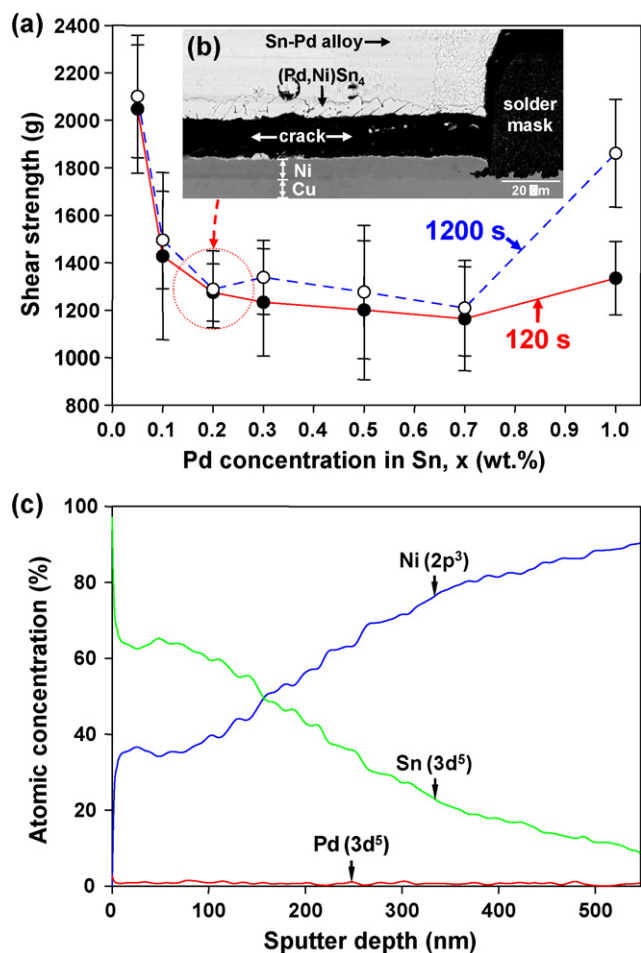


Fig. 7. (a) Shear strength of the Sn-*x*Pd/Ni joints as a function of Pd concentration (*x*). (b) Typical fracture of a Sn-0.2Pd/Ni joint after the shear test. (c) μ -XPS depth profiles of the atomic concentrations of the board-side fracture surface for the Sn-0.2Pd/Ni joint after the HSBS test.

a relatively high level of 13.1 at.% (average) at the interface, i.e. $(\text{Pd}_{0.34}\text{Ni}_{0.66})\text{Sn}_4$, which is one order of magnitude larger than that distributed away from the interface. The growth of the high Ni-containing $(\text{Pd}_{0.34}\text{Ni}_{0.66})\text{Sn}_4$ layer at the expense of the low Ni-containing $(\text{Pd},\text{Ni})\text{Sn}_4$ domains scattered in the Sn matrix suggests that the phase tends to become more Ni-bearing, i.e., $(\text{Pd}_{0.34}\text{Ni}_{0.66})\text{Sn}_4$.

3.3. High-speed-ball-shear test

To quantify mechanical response of the various interfacial microstructures derived from different Pd concentrations (*x*), the HSBS test was used. Fig. 7a shows a plot of the shear strength of the Sn-*x*Pd/Ni joints as a function of the Pd concentration after the test. The solid and dashed lines represent the reaction results at 120 s and 1200 s, respectively. These data were obtained using the same experimental conditions, including a shear tool module (3 kg), shear speed (2 m/s), shear height (60 μm), and reaction temperature (250 °C). The shear strengths were approximately independent of the reaction time (i.e., 120 s and 1200 s), which dramatically dropped, leveled off, and then rose with increasing *x*. The highest strength, ~2100 g, was measured at *x*=0.05. When *x* increased to 0.2–0.7, the value was substantially reduced to 1200–1400 g, which is about 33–43% lower than that of the Sn-0.05Pd case (Fig. 7a). Interestingly, the strength increased at *x*=1, specifically for the case of the long-term reaction (i.e., 1200 s). All of the solder joints

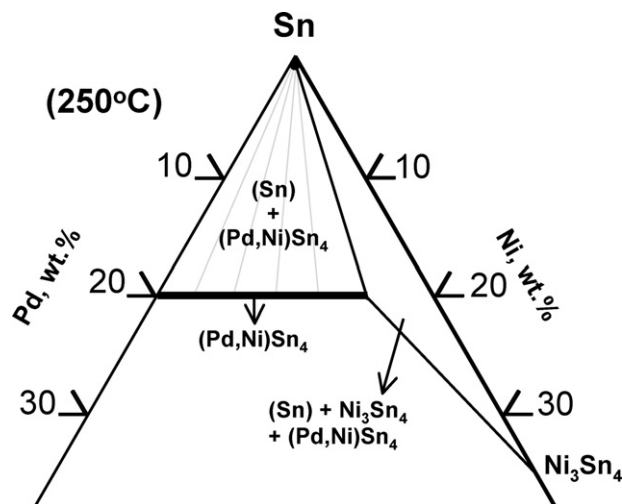


Fig. 8. Schematic drawing of the Sn-rich corner of the Pd-Ni-Sn phase diagram at 250 °C. This isotherm was adapted from Ref. [14] and redrawn in this study.

fractured through the Sn-*x*Pd/Ni interface after the HSBS test, with the exception of the Sn-0.05Pd case, where most of the fractures actually occurred either in the solder region or within the substrate. The fracture mode indicates that the formation of a single Ni₃Sn₄ phase at the interface has a better resistance against the HSBS impact than the Sn-0.05Pd alloy.

Fig. 7b shows a cross-section of the Sn-0.2Pd/Ni interface after a 120-s reaction and a manual shear test, providing a better understanding of the failure mode of a dense layer of $(\text{Pd},\text{Ni})\text{Sn}_4$ formed at the interface. The joint failed approximately through the interface between the $(\text{Pd},\text{Ni})\text{Sn}_4$ layer and the Ni substrate, unlike the fracture through the solder region observed in the Sn-0.05Pd case. To identify a more exact fracture location, a μ -XPS elemental depth profile analysis from the facade of the board-side fracture was performed. In the μ -XPS analysis, the depth scale was defined based on a known SiO₂ film that was sputtered by Ga⁺ ions at an etching rate of 2.1 nm/s. The Sn concentration progressively decreased from about 60 at.%, while the Ni concentration increased from about 40 at.% as a function of the sputtered depth (Fig. 7c). No meaningful Pd signal could be detected from the entire profile, reflecting the fact that the fracture does not occur within the $(\text{Pd},\text{Ni})\text{Sn}_4$ layer. The mixture of Ni and Sn extended to a depth of about 500 nm (Fig. 7c), which is comparable to the thickness of the Ni₃Sn₄ shown in Fig. 4a. The results of the μ -XPS analysis indicate that the Sn-0.2Pd/Ni joint fails approximately through the $(\text{Pd},\text{Ni})\text{Sn}_4/\text{Ni}_3\text{Sn}_4$ interface.

Interestingly, the fracture translated from the $(\text{Pd},\text{Ni})\text{Sn}_4/\text{Ni}_3\text{Sn}_4$ interface to the $(\text{Pd},\text{Ni})\text{Sn}_4$ layer when *x* further increased to 1, providing a possible link between the improved shear strength and the observation of less voiding at the $(\text{Pd},\text{Ni})\text{Sn}_4/\text{Ni}_3\text{Sn}_4$ interface. The combined results of the HSBS test and failure mode suggest that the Pd concentration should be reduced to a level below 0.2 wt.% to prevent the formation of an undesired $(\text{Pd},\text{Ni})\text{Sn}_4$ layer at the interface.

4. Discussion

4.1. Low Pd-concentration case (*x* = 0.05, 0.1, 0.2, and 0.3)

The soldering reaction between Ni and the Sn-*x*Pd alloys strongly depended on the Pd concentration. The reaction product transformed from a single layer of Ni₃Sn₄ to a dual layer of $(\text{Pd},\text{Ni})\text{Sn}_4$ -Ni₃Sn₄ as *x* increased from 0.05 to 0.2 (or higher). This Pd-dependent reaction can be rationalized using the Pd-Ni-Sn isotherm (Fig. 8 [14]) as follows. According to Fig. 8, one three-phase

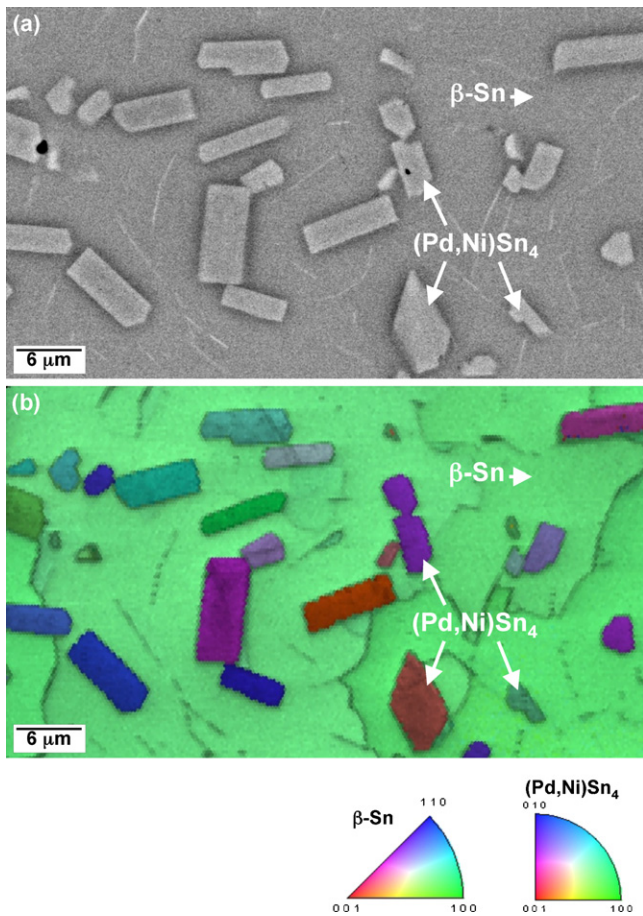


Fig. 9. (a) Backscattered electron image showing the solder region near the Sn–0.5Pd/Ni interface that had experienced a 250 °C reaction for 300 s. (b) An EBSD image quality (IQ)-inverse pole figure (IPF) of (a).

field (Sn) + Ni₃Sn₄ + (Pd,Ni)Sn₄, and two two-phase fields (Sn) + Ni₃Sn₄ and (Sn) + (Pd,Ni)Sn₄, are in equilibrium with the liquid Sn phase (Sn). The solubility of Pd in both Sn and Ni₃Sn₄ is very limited; thus, the two-phase field (Sn) + Ni₃Sn₄ is narrow in size and approximates the border of pure Sn + pure Ni₃Sn₄. At a low *x* value (e.g., 0.05), the Sn–Pd alloy represents a tie-line to the Ni₃Sn₄, meaning that the formation of the Ni₃Sn₄ adjacent to the low Pd-containing alloy is thermodynamically stable. In contrast, as *x* slightly increased, say to 0.2 wt.%, the growth of a continuous (Pd,Ni)Sn₄ phase at the interface became stable because tie-lines existed between the (Pd,Ni)Sn₄ and (Sn) containing a relatively high *x*. Thus, the (Pd,Ni)Sn₄ and Ni₃Sn₄ phases coexisted adjacent to the (Sn) at an intermediate *x* value (e.g., 0.1) when the three-phase equilibrium (Sn) + Ni₃Sn₄ + (Pd,Ni)Sn₄, was reached.

In the Sn–0.1Pd/Ni case, however, the (Pd_{0.26}Ni_{0.74})Sn₄ grains progressively spalled away from the interface, leaving the Ni₃Sn₄ with a limited amount of (Pd_{0.26}Ni_{0.74})Sn₄ at the interface after 180 s (Fig. 5). This implies that the formation of both (Pd_{0.26}Ni_{0.74})Sn₄ and Ni₃Sn₄ at the interface is not stable during a long-term reaction. This time-dependent behavior seems to be contrary to the thermodynamic rationalization explained above. There are two possibilities for this deviation. The first is derived from the Pd concentration drop during the reaction. The (Pd_{0.26}Ni_{0.74})Sn₄ clearly grows at the interface at the expense of the Pd within the Sn–Pd alloy. This causes a reduction in the Pd concentration, which might shift the equilibrium relationship from (Sn)–Ni₃Sn₄–(Pd_{0.26}Ni_{0.74})Sn₄ to (Sn)–Ni₃Sn₄ if *x* is reduced to a low level, say 0.05 (Fig. 8). As a consequence, the coexistence of

Ni₃Sn₄ and (Pd_{0.26}Ni_{0.74})Sn₄ at the interface is destroyed, and an even more stable microstructure, where only the Ni₃Sn₄ phase exists at the interface, is established. To validate this assumption, a careful estimation of the Pd concentration drop (ΔC_{Pd}) should be performed.

According to [18,23], the ΔC_{Pd} under different combinations of pad diameter (d_{pad}) and joint diameter (d_{joint}) can be expressed as,

$$\Delta C_{Pd} = \frac{3}{2} \left(\frac{d_{pad}^2}{d_{joint}^3} \right) \left(\frac{\rho_{(Pd,Ni)Sn_4}}{\rho_{Sn-Pd}} \right) w_{Pd} \delta_{(Pd,Ni)Sn_4} \quad (1)$$

where $\rho_{(Pd,Ni)Sn_4}$ and ρ_{Sn-Pd} represent the density of (Pd,Ni)Sn₄ and the Sn–Pd alloy, respectively. w_{Pd} represents the Pd content of (Pd,Ni)Sn₄, and $\delta_{(Pd,Ni)Sn_4}$ represents the (Pd,Ni)Sn₄ thickness.

In this study, d_{pad} and d_{joint} are 375 μm and 1200 μm, respectively, as depicted in Fig. 1. $\rho_{(Pd,Ni)Sn_4}$ and ρ_{Sn-Pd} can be taken to be ~8.175 g/cm³ (the density of PdSn₄) and ~7.31 g/cm³ (the density of pure Sn), respectively. w_{Pd} and $\delta_{(Pd,Ni)Sn_4}$ for the Sn–0.1Pd/Ni case were measured to be ~5.6 wt.% and ~3.7 μm (average) after a 120-s reaction. Accordingly, the resulting ΔC_{Pd} is ~0.0028 wt.%, which is two orders of magnitude smaller than the initial Pd concentration (0.1 wt.%). This estimation indicates that the Pd concentration remains approximately the same during the reaction, suggesting that ΔC_{Pd} might not be a key factor responsible for the microstructural evolution observed in Fig. 5.

An alternative explanation for the disappearance of (Pd_{0.26}Ni_{0.74})Sn₄ from the interface is attributed to the fact that the Ni content in (Sn) increases over time. The dissolution of Ni changes the adjacent Sn–0.1Pd alloy into a Ni-containing Sn–0.1Pd alloy, where the (Sn) is locally in equilibrium with the Ni₃Sn₄ and (Pd,Ni)Sn₄. Therefore, the composition of the Sn–Pd alloy (or the Ni and Pd concentrations) neighboring the interface is different from that of the bulk region. As the reaction time increases, the concentration gradient continues to deliver the Ni atoms to the other region unsaturated with Ni, thereby increasing the extent of the (Sn)–Ni₃Sn₄–(Pd,Ni)Sn₄ three-phase equilibrium. Accordingly, the (Pd,Ni)Sn₄ phase has no need to maintain its stability by attaching itself to the Ni₃Sn₄ at the interface; instead, it can grow anywhere with sufficient Ni. The possibility of this alternative mechanism is currently being evaluated using Ni-doping Sn–Pd alloys for the reaction.

Kinetically, intermetallic spalling usually follows the Ostwald ripening process [24,25], in which atoms of the smaller grains are driven to the larger grains due to the concentration gradient that is created via the Gibbs–Thomson effect [26]. The spalling phenomenon reported in [24,25], however, was induced by the exhaustion of the substrate (i.e., Cu); this results in a compound layer (i.e., Cu₆Sn₅) that is in direct contact with the oxidized Cr layer, which has poor wettability with Cu₆Sn₅. This is unlike the situation encountered in this study, where most of the (Pd_{0.26}Ni_{0.74})Sn₄ detaches from the interface, even though the substrate has not yet been exhausted. We proposed the convection of molten solder to be the driving force for the detachment of the unstable (Pd_{0.26}Ni_{0.74})Sn₄ grains from the interface (Fig. 5).

4.2. High Pd-concentration case ($x \geq 0.5$)

According to the literature [27], the saturation solubility of Pd in Sn–Ag solder at 250 °C (i.e., the reaction temperature used in this study) is about 0.4 wt.%. Assuming that it is compatible with the situation of pure Sn, the high Pd-containing alloys (0.5–1 wt.% Pd) enter the so-called “paste zone”, in which the alloys actually consist of liquid Sn and PdSn₄ phases. This scenario is distinctly different from its counterpart (i.e., the low Pd-concentration case) in that only one liquid Sn phase survives at 250 °C. In other words, the Pd

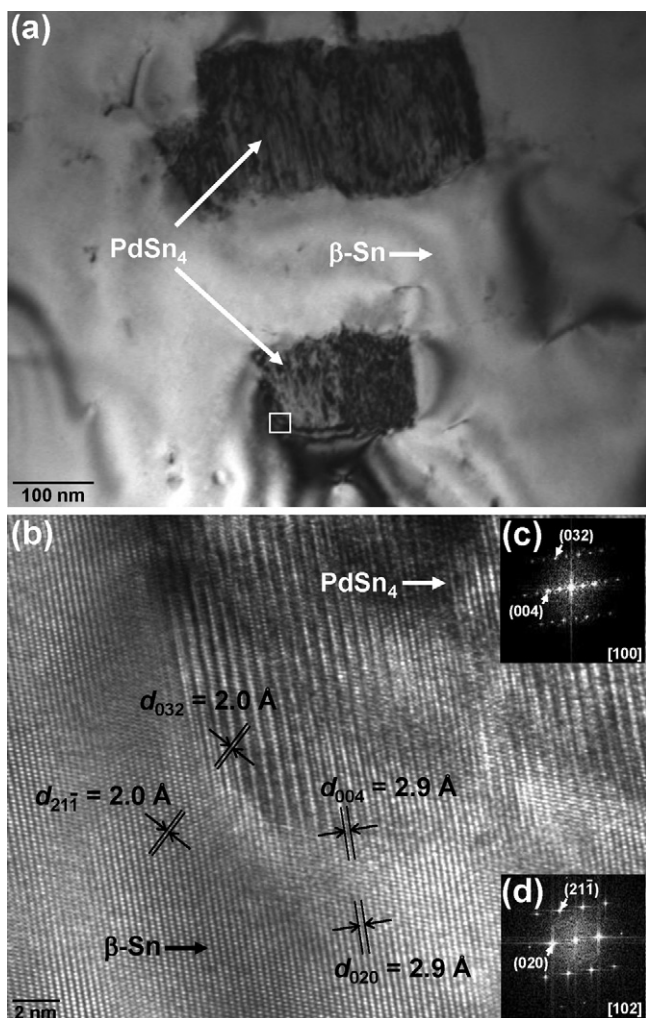


Fig. 10. (a) TEM bright field image of the PdSn₄ domains in the β-Sn matrix. (b) Magnified image of the area labeled by the square in (a). (c–d) Fast Fourier transform (FFT) obtained from the PdSn₄ and β-Sn lattice information provided in (b), respectively.

in the high Pd-concentration alloys exists in the forms of Pd atoms and PdSn₄.

During soldering, the dissolution of the Ni substrate transforms the binary Sn–Pd alloy into a ternary Sn–Pd–Ni system, shifting the equilibrium from (Sn)–PdSn₄ to (Sn)–(Pd,Ni)Sn₄ (Fig. 8). As a result, the pure PdSn₄ phase is no longer stable but is required to transform itself into a Ni-containing phase, i.e. (Pd,Ni)Sn₄, instead. This change drives the PdSn₄ grains originally in the (Sn) matrix to migrate towards the interface, to gain Ni from the Ni substrate, shifting to the stable (Pd,Ni)Sn₄ phase. The phenomenon wherein the (Pd,Ni)Sn₄ grains tend to migrate to the interface and become more Ni-containing phases, as shown in Fig. 6, supports this view.

Fig. 9a and b shows a BEI together with an image produced by electron backscatter diffraction-orientation image microscopy (EBSD-OIM) of the solder region neighboring the interface, providing further information regarding the crystallographic correlation of the (Pd,Ni)Sn₄ grains with the solder matrix. The results of EBSD-OIM indicate that the isolated phase domains have the same PdSn₄-based crystal structure (FC orthorhombic; space group: *Aba2*) and randomly distribute in the solder matrix, independent of the β-Sn orientation. This incoherent crystallographic relationship shows that the orientations of the scattered (Pd,Ni)Sn₄ grains are unrestricted by the Sn matrix during soldering. This lack of restriction in orientation occurs because the crystal structure of β-Sn was

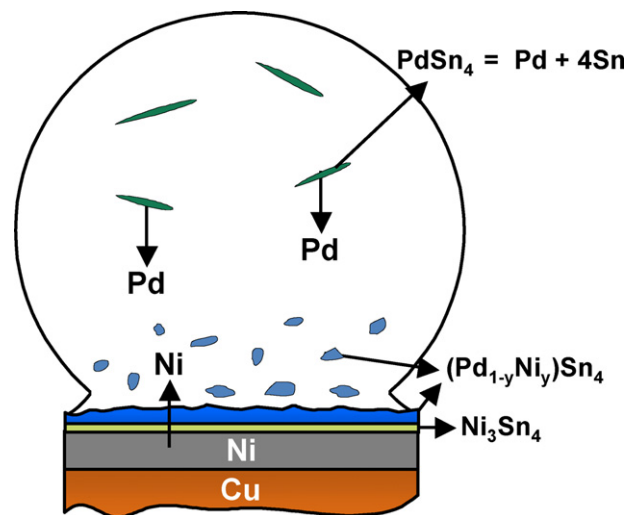
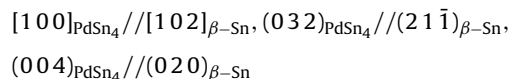


Fig. 11. Schematic drawing of the (Pd_{1-y}Ni_y)Sn₄ growth mechanism in the high Pd-concentration case.

destroyed in the molten state. The observation provides a proof of the two-phase mixture layer of (Pd,Ni)Sn₄–(Sn) shown in Fig. 6 was well developed during the liquid–solid reaction.

Fig. 9 also reveals that there are many white, strip-like grains uniformly scattered inside the Sn matrix. A similar result can also be observed in Figs. 2, 5 and 6. The thickness of the strip-like grains, however, is too thin for their composition/crystal structure to be accurately measured though FE-EPMA or EBSD (Fig. 9b). According to the Pd–Sn phase diagram [13], the PdSn₄ intermetallic is the only phase in equilibrium with the β-Sn when the Pd concentration in a Sn–Pd alloy is less than 20%. It is, therefore, presumed that these tiny grains represent the PdSn₄ phase, which form in the solidification stage due to the solubility limit. To further verify this assumption, FE-TEM was employed to identify the crystal structure of the compound and the crystallographic correlation with the β-Sn matrix. Fig. 10a shows a TEM bright-field (BF) image of the solder region after reacting at 250 °C. Two isolated phase domains in the Sn matrix can be clearly observed in this figure. Fig. 10b displays a lattice image of the area neighboring the grain boundary between one of the isolated domain and the β-Sn phase. The insets (Fig. 10c and d) show electron diffraction patterns from the two phases, which were obtained using the lattice image (Fig. 10b) simulated by fast Fourier transform (FFT) through the Gatan DigitalMicrograph software (version 1.83). The lattice information provided in Fig. 10b and c indicates that the isolated grains are indeed based on the PdSn₄ crystal structure and that a coherent orientation relationship exists between the PdSn₄ phase and the β-Sn matrix:



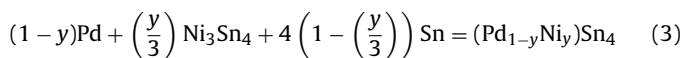
This coherent crystallographic correlation suggests that these strip-like PdSn₄ grains in the β-Sn matrix (Figs. 2, 5, 6 and 9) are most likely derived from the precipitation during solidification, unlike the growth mechanism of the chunk-like (Pd,Ni)Sn₄ grains shown in Fig. 9.

The resettlement of PdSn₄ from the solder matrix caused a significant growth of the phase at the interface, especially in the high Pd-concentration case (Fig. 6). The resettlement relies on the Pd atoms diffusing to the interface, instead of an unity of PdSn₄, as

shown in Fig. 11. Therefore, the PdSn₄ should decompose first according to the following equation:



The Pd atoms should then diffuse to the interface and react with the Ni₃Sn₄ into the Ni-bearing (Pd_{1-y}Ni_y)Sn₄, according to Eq. (3):



Eq. (3) indicates that the formation of one mole of (Pd_{1-y}Ni_y)Sn₄ at the interface requires $y/3$ mole of Ni₃Sn₄ and $4(1 - y/3)$ mole of Sn. In the case of $x=0.5$, y is determined to be 0.36; that is, 0.12 mole of Ni₃Sn₄ and 3.52 mole of Sn will be depleted when one mole of (Pd_{0.64}Ni_{0.36})Sn₄ is produced. This provides a possible explanation as to why the Ni₃Sn₄ growth was retarded when a layer of (Pd,Ni)Sn₄ nucleated over the Ni₃Sn₄ (Figs. 3 and 6). Another explanation is that the (Pd,Ni)Sn₄ phase is very thick and continuous, so the atomic interdiffusion is significantly inhibited and the Ni₃Sn₄ growth is retarded [28]. The calculated result also shows that a plenty of Sn is depleted in the growth of (Pd_{0.64}Ni_{0.36})Sn₄. However, the enormous depletion of Sn did not produce significant voids in the solder matrix (Fig. 6) because the solder was in the molten state during the reaction; thus, any vacancy produced should be filled with the molten solder very quickly.

The growth mechanism of (Pd,Ni)Sn₄ aforementioned is quite similar to that of the layered-type (Au,Ni)Sn₄ [17,29,30] and (Cu,Ni)₆Sn₅ [31,32] developed at the solder/Ni interface, whereas the decomposition of PdSn₄ (Eq. (2)) and the diffusion of Pd atoms (Eq. (3)) both occurred in the liquid solder, unlike AuSn₄ or Cu₆Sn₅ in a solid. Consequently, a much higher growth rate of (Pd,Ni)Sn₄ was obtained in the present work.

5. Conclusions

The liquid–solid reaction between Sn–Pd alloy and Ni was found to be dominated not only by the Pd concentration but also the reaction time. Ni₃Sn₄ and (Pd,Ni)Sn₄ were the two predominant intermetallic compounds observed, which grew at the interface either separately or simultaneously depending on two factors (i.e., the Pd concentration and the reaction time). When the Pd concentration of the Sn–Pd alloy was low, e.g., 0.05 wt.%, only Ni₃Sn₄ was observed after reacting at 250 °C for 120–1200 s. When the Pd concentration increased to 0.1 wt.% and the reaction time was relatively short (60–150 s), discontinuous (Pd,Ni)Sn₄ grains scattered above the Ni₃Sn₄ layer were produced. Interestingly, most of the (Pd,Ni)Sn₄ grains disappeared, but the Ni₃Sn₄ remained after 300 s. When the Pd concentration further increased to 0.2 wt.% or higher, (Pd,Ni)Sn₄ developed as a continuous layer in contact with the Ni₃Sn₄.

The mechanical properties of the Sn–Pd/Ni joints were also rather sensitive to the Pd concentration, as demonstrated by the HSBS test. It was found that the shear strength dramatically degraded when the Pd concentration was equal to or greater

than 0.2 wt.%, and the formation of the (Pd,Ni)Sn₄–Ni₃Sn₄ dual layer was the root cause of this degradation. The results of this study indicate that the Pd concentration has a significant influence on the Sn–Pd/Ni reaction. The Pd concentration in the Sn–Pd joints should be reduced to prevent the dual-layer structure of (Pd,Ni)Sn₄–Ni₃Sn₄ from being established at the interface.

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